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TITLE: SURFACE PURIFYING METHOD

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ABSTRACT:

PROBLEM TO BE SOLVED: To easily remove contaminants such as particles deposited on a wafer or contaminant metals in one method by peeling an adhesive tape adhered to a surface to be washed.

SOLUTION: A tape 13 having an adhesive substance 12 is adhered to a dirty wafer 11 made by the resist washing, heated by a lamp 14 to harden the substance 12 and peeled off to result in the remarkable reduction of particles deposited on the wafer and amount of contamination metals. Thus it is possible to remove deposited particles and contamination metals which were treated by

separate washing liqs. by one washing method using the tape 13 and hence simplify the washing process, without consuming much chemical liqs. and needing the drying.

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